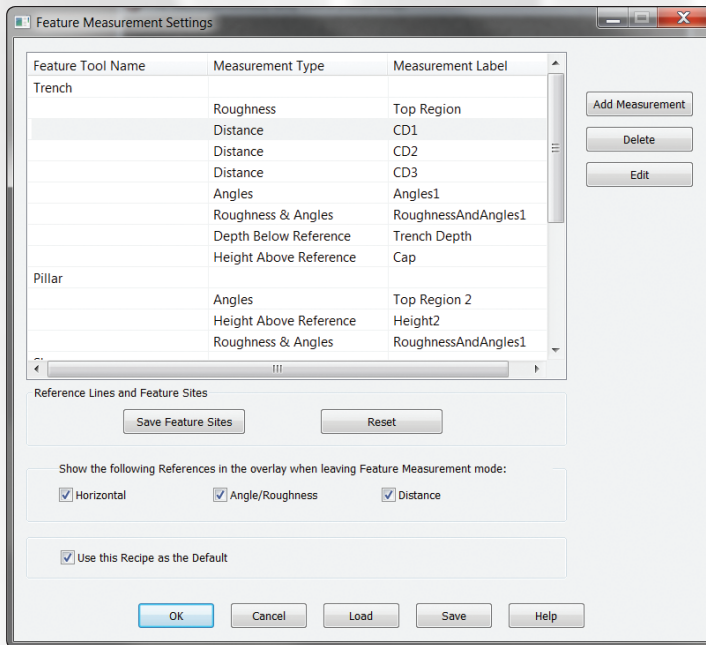# Automated Measurement for Semiconductor Features

Just Click... and That's it.

3 Levels of 'Single Click' Automation:

1. Fully Characterize a Feature with a Single Click

2. Characterize a Multiple Feature Image with a Single Click Using PCI-AM 'Magic Wand' Tool

3. Use the New PCI-AM Batch Automation to Process and Measure an Entire Folder Similar Images **NEW**

Create and Save Recipes for Measurement Types, Locations and Labels. Load the Recipe for Similar Images.
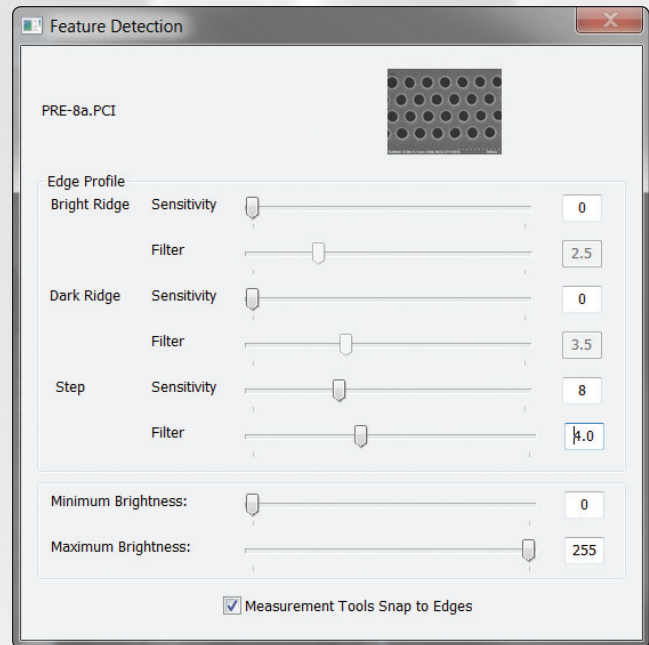
Our 3 Edge Detection Techniques allow you to work with more types of images and more types of features.

PCI-AM Benefits:

- Save Time
- Increase Measurement Consistency
- Generate Reports Easily with Images and Data
- Increase Measurement Accuracy
- Export Data Easily Into CSV File

QUARTZ IMAGING CORPORATION

SPECIALIZED SOLUTIONS FOR ELECTRONIC DEVICE LABS & ANALYSIS

6190 Agronomy Rd, Suite 406 Vancouver, BC Canada V6T 1Z3
Phone: +1-604-488-3911 • Fax: +1-604-488-3922 • inform2@quartzimaging.com • www.quartzimaging.com

FOR A FASTER SMARTER LAB

Automated Measurement for Semiconductor Features

Types of Automated Measurements

Trenches (Spaces) and Pillars (Lines)

- CD Width
- Angles – Sidewall and Center
  - Multiple Regions in Feature
- Line Edge Roughness
- Line Width Roughness
- Distances Below and Above Reference Line
- Averages of the Above Measurements

Trench Measurements

Macro Cell

- Multiple Measurements in Complex Features with a Single Click

Shapes

- Area and Perimeter
- Ideal Shape Deviation
- Aspect Ratio
- Major and Minor Axes
- Collinearity
- Tilt

Macro Cell

Other New Valuable PCI-AM Features

- "Point and Shoot" Horizontal and Vertical Measurement Tools Utilize Edges
- Regular PCI Measurement Tools will "Snap" to the Edges in PCI-AM
- Predetermine the number and exact location of CD measurements relative to the reference line **NEW**
- Improved edge detection capabilities **NEW**

We Can Custom Develop any Specific Measurements *You* Require.

Shape Measurements